

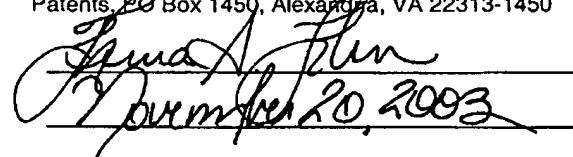
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yong-Pil Han et al.
Serial No.: 09/498,303
Filed: February 4, 2000
For: HF Vapor Phase Wafer Cleaning and Oxide Etching

Confirmation No. 8629
Group Art Unit: 1763
Examiner: T. Dang

COMMISSIONER FOR PATENTS
P. O. Box 1450
ALEXANDRIA, VIRGINIA 22313-1450

I hereby certify that this correspondence is being deposited on the date shown below with the United States Postal Service with sufficient postage as first class mail, under 37 CFR 1.8(a), in an envelope addressed to: Commissioner For Patents, P.O. Box 1450, Alexandria, VA 22313-1450



_____AMENDMENT

This is in response to the Examiner's Action mailed May 21, 2003.

A petition for three-month extension of time accompanies this amendment.

Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.